



Attorney Docket No. 0756-7283

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Koichiro TANAKA et al.
Serial No. 10/815,813
Filed: April 2, 2004
For: METHOD OF FABRICATING
SEMICONDUCTOR DEVICE
UTILIZING LASER IRRADIATION

) Group Art Unit: 2814
) Examiner: Alonzo Chambliss

) CERTIFICATE OF MAILING

) I hereby certify that this correspondence is
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) 2007.

) Adam M. Stamp

DO NOT ENTER: /AC/ (09/07/2007)

RESPONSE

Honorable Commissioner of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The Official Action mailed November 2, 2007, has been received and its contents carefully noted. This response is filed within three months of the mailing date of the Official Action and therefore is believed to be timely without extension of time. Accordingly, the Applicant respectfully submits that this response is being timely filed.

The Applicant notes with appreciation the consideration of the Information Disclosure Statements filed on April 2, 2004; January 13, 2006; and September 12, 2006. Applicant notes the *partial* consideration of the Information Disclosure Statement filed on August 17, 2006. The Applicant's representative conducted a telephone conference with Examiner Chambliss on December 8, 2006, during which agreement was reached that the foreign references cited at the bottom of page 1 of 2 from the Information Disclosure Statement filed August 17, 2006, including their attached translations, were fully considered by Examiner Chambliss. Examiner Chambliss explained that he placed an "X" through the dates and translation information out of a belief that such information is not of concern to the Publications Department. Also, agreement was reached that the Applicant would summarize this understanding in the